

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S109	14	(semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with (vapor or steam)) and ((sens\$3 or detect\$3) with (temperature and overheat\$3)) with control\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 11:11
S110	4	((semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with (vapor or steam)) and ((sens\$3 or detect\$3) with temperature) with control\$4).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 11:09
S108	1216	(semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with (vapor or steam)) and ((sens\$3 or detect\$3) with temperature) with control\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 11:08
S107	4	((semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with vapor or steam) and ((sens\$3 or detect\$3) with temperature) with control\$4).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 11:07
S106	53	(semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with vapor or steam) and ((sens\$3 or detect\$3) with temperature and overheat\$3) with control\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 11:07
S105	1356	(semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with vapor or steam) and ((sens\$3 or detect\$3) with temperature) with control\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 11:07

EAST Search History

S10 3	28	S101 and (heat\$3 and (sens\$3 or detect\$3) with temperature)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 11:02
S10 4	52	S102 and (heat\$3 and (sens\$3 or detect\$3) with temperature)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 10:58
S10 2	493	134/58R,58R,95.2,98.1,99.1,102.1, 102.3,105,200,902.ccls. and @pd>"20041025"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 10:56
S10 1	222	((takayuki near2 toshima).in.) or ((kinya near2 ueno).in.) or ((miyako near2 yamasaka).in.) or ((hideyuki near2 tsutsumi).in.) or ((yuji near2 kamikawa).in.) and @pd>"20041025"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 10:55
S74	5050	134/58R,58R,95.2,98.1,99.1,102.1, 102.3,105,200,902.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 10:55
S48	359	((takayuki near2 toshima).in.) or ((kinya near2 ueno).in.) or ((miyako near2 yamasaka).in.) or ((hideyuki near2 tsutsumi).in.) or ((yuji near2 kamikawa).in.)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/10/31 10:55